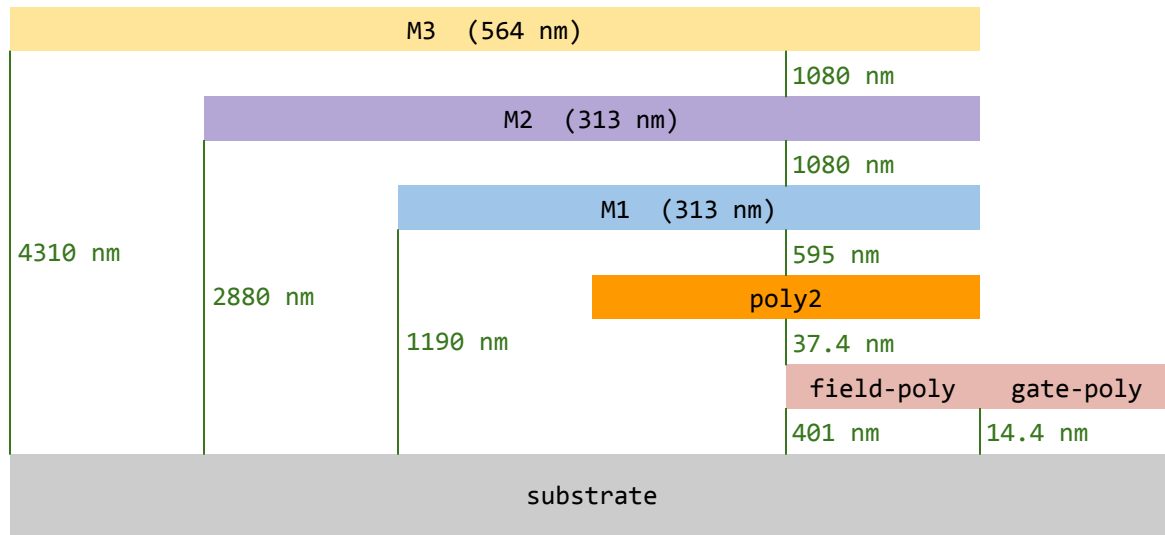**OnSemi C5N process layer stackup dimensions extracted from published data**

* thickness from resistance

* distance from capacitance value

Dan White

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